

IN THE CLAIMS:

Please cancel claims 28 and 35, and amend the claims as follows:

1-21. (Cancelled)

22. (Currently Amended) An apparatus for vaporizing a solid precursor, comprising:

a housing having an inlet for receiving a carrier gas and an outlet in fluid communication with a sealable interior volume;

at least two surfaces comprising a mesh material contained in the housing having a solid chemical precursor applied thereto, wherein the solid chemical precursor includes a tantalum-containing precursor or a tungsten-containing precursor; and

a heating member ~~in thermal communication with~~ contained within a wall of the housing, wherein at least one of the at least two surfaces is in thermal communication with the wall of the housing.

23. (Previously Presented) The apparatus of claim 22, wherein the at least two surfaces are spaced to allow passage of the carrier gas therebetween.

24. (Previously Presented) The apparatus of claim 22, wherein the at least two surfaces are formed of a material selected from the group consisting of stainless steel and ceramic.

25. (Previously Presented) The apparatus of claim 22, wherein the outlet is configured to operably couple to a reaction chamber of a deposition chamber.

26. (Previously Presented) The apparatus of claim 25, wherein the deposition chamber is selected from the group consisting of an ALD chamber, a CVD chamber, and an evaporative coating chamber.

27. (Previously Presented) The apparatus of claim 25, wherein the deposition chamber is an ALD chamber.

28. (Cancelled)

29. (Currently Amended) The apparatus of claim 22, wherein ~~[[the]]~~ a heating member is contained in one of the at least two surfaces.

30. (Previously Presented) The apparatus of claim 22, wherein one of the at least two surfaces is coupled to the housing.

31. (Previously Presented) The apparatus of claim 22, wherein the at least two surfaces have a form selected from the group consisting of an s-shape, a linear shape, and a cone shape.

32. (Currently Amended) An apparatus for vaporizing a solid precursor, comprising:

a housing having an inlet for receiving a carrier gas and an outlet in fluid communication with a sealable interior volume;

at least two cone shaped surfaces contained in the housing having a solid chemical precursor applied thereto; and

a heating member ~~in thermal communication with~~ contained within a wall of the housing, wherein at least one of the at least two surfaces is in thermal communication with the wall of the housing.

33. (Previously Presented) The apparatus of claim 32, wherein the at least two surfaces are spaced to allow passage of the carrier gas therebetween.

34. (Previously Presented) The apparatus of claim 32, wherein the at least two surfaces are formed of a material selected from the group consisting of stainless steel and ceramic.

35. (Cancelled)

36. (Currently Amended) The apparatus of claim 32, wherein ~~[[the]]~~ a heating member is contained in one of the at least two surfaces.

37. (Previously Presented) The apparatus of claim 32, wherein one of the at least two surfaces is coupled to the housing.

38. (Previously Presented) The apparatus of claim 32, wherein the solid chemical precursor includes a tantalum-containing precursor or a tungsten-containing precursor.